



# Micro/Nano Fabrication Center

(Approved Rates April 2015)

<b>SERVICE</b>	<b>Internal</b>	<b>External</b>
Lithography Exposure	50	75
Spin Coater	33	37
PVD Evaporation	69	77
Oxidation/Anneal Furnace	64	100
Plasma Clean	36	40
Plasma Etch	50	75
LPCVD Doped PolySi	200	250
LPCVD LTO Deposition	200	250
LPCVD Nitride Deposition	300	350
LPCVD Undoped Polysi Deposition	200	250
PECVD Deposition	79	90
Dicing Diamond Saw	77	165
Wet Bench/Clean/Etch/Hood	98	110
Profiler Alpha Step 200	11	13
Profiler KLA Tencor P-15	50	56
Reflectometer Filmetrics F20	7	11
Four Point Probe	8	12
Probestation & Microscope	10	12
Labor	50	56
Nitrogen	125	N/A
Cleanroom Entrance Fee (per day)	20	TBD
Cleanroom Entrance Fee (per month)	N/A	550

If you have any questions please contact Facility Manager, Omid Mahdavi at [omidm@email.arizona.edu](mailto:omidm@email.arizona.edu)